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Strain in epitaxial Bi$_2$Se$_3$ grown on GaN and graphene substrates: A reflection high-energy electron diffraction study

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Topological insulator (TI) has been one of the focus research themes in condensed matter physics in recent years. Due to the relatively large energy bandgap, Bi$_2$Se$_3$ has been identified as one of the most promising three-dimensional (3D) topological insulators (TIs) with application potentials. Epitaxial Bi$_2$Se$_3$ by molecular-beam epitaxy has been reported by many groups using different substrates. A common feature is that Bi$_2$Se$_3$ grows readily along the c-axis direction irrespective of the type and condition of the substrate. Because of the weak van der Waals interaction between Bi$_2$Se$_3$ quintuple layers, the grown films are reported to be strain-free, taking the lattice constant of the bulk crystal. At the very initial stage of Bi$_2$Se$_3$ deposition, however, strain may still exist depending on the substrate. Strain may bring some drastic effects to the properties of the TIs and so achieving strained TIs can be of great fundamental interests as well as practical relevance. In this work, we employ reflection high-energy electron diffraction to follow the lattice constant evolution of Bi$_2$Se$_3$ during initial stage depositions on GaN and graphene, two very different substrates. We reveal that epitaxial Bi$_2$Se$_3$ is tensile strained on GaN but strain-free on graphene. Strain relaxation on GaN is gradual. © 2015 AIP Publishing LLC. [http://dx.doi.org/10.1063/1.4929697]

Topological surface (interface) state represents a novel quantum state of matter, which has attracted a lot of research attention lately for interests in fundamental science as well as practical applications. Bi$_2$Se$_3$ is a representative three-dimensional (3D) topological insulator (TI) having the rhombohedral crystal structure (R3m). The crystal of Bi$_2$Se$_3$ consists of stacks of quintuple layers (QLs) of chemically bonded Se-Bi-Se-Bi-Se and is held by the van der Waals (vdW) forces. Such a structural and bonding property of Bi$_2$Se$_3$ leads to some unique growth properties that are characteristics of the vdW epitaxy.

Originating from the different topological electronic structures of matter, epitaxial Bi$_2$Se$_3$ layers can modify the topological states, and an experimental study of strain in TI is fundamentally interesting and practically important for application purposes. Bi$_2$Se$_3$ was deposited in a customized Omicron MBE reactor from elemental Bismuth (Bi) and Selenium (Se) sources in the Knudsen cells. The cell temperature of the Bi source was 500 °C and that of Se was at 110 °C. For the latter, the orifice was heated at 210 °C by a second set of filaments to prevent Se condensation. The flux ratio between Bi and Se was 1:10 and the film growth rate was 0.2 QLs/min according to post-growth film thickness measurements by cross-sectional transmission electron microscopy. The substrate temperature was 200 °C throughout. Ga-face GaN substrate was thermally treated in ultrahigh vacuum (UHV) until a clean (1 × 1) pattern emerged in the RHEED. Multilayer graphene was prepared by heating Si-face 4H-SiC wafer at ≥1200 °C following the procedure documented in the literature. During Bi$_2$Se$_3$ deposition, the sample surface was constantly monitored by the RHEED operated at 10 keV. The diffraction patterns on the phosphorus screen were captured by a high-speed CCD camera (AVT Stingray F046B) and the intensity data were acquired by a 1394 card and processed by a desktop computer. The spacing D between diffraction streaks was extracted by locating the intensity peak positions of the line profiles across the first-order (01) and (01) streaks through computer fitting. The lattice constant of the deposit, $a_{\text{sample}}$, was derived from D by the formula

$$\frac{a_{\text{sample}}}{a_{\text{ref}}} = \frac{D_{\text{ref}}}{D_{\text{sample}}},$$

where $a_{\text{ref}}$ refers to the (in-plane) lattice constant of a reference film, e.g., the substrate. $D_{\text{sample}}$ and $D_{\text{ref}}$ are the measured inter-diffraction streak spacing of the deposit and the
reference material (substrate), respectively, reflecting the reciprocal lattice constants of the corresponding materials. STM measurements of the grown films were carried out in an adjacent UHV chamber using an Omicron STM facility at room-temperature (RT). For all measurements, the constant current mode was used. The tunneling current and sample bias were 0.1 nA and 1.0 V, respectively. To enhance features of surface steps and defects, differential images obtained by digitally differentiating the intensity over space coordinates were also presented besides the topographic images.

On GaN, growth of Bi$_2$Se$_3$ proceeds by formation of an initial polycrystalline layer followed by gradual crystallization upon increasing deposit thickness. Figs. 1(a)–1(c) present the RHEED patterns of a sample during initial stage deposition on GaN. One observes that the streaky pattern of the smooth GaN surface [Fig. 1(a)] changes quickly to a ring pattern superimposed with streaks corresponding to Bi$_2$Se$_3$ at about 1 QL [Fig. 1(b)]. The ring pattern then recedes gradually and gives way to streaks again with increasing film thickness [Fig. 1(c)]. The ring pattern signifies a polycrystalline nucleation layer of Bi$_2$Se$_3$ at the beginning, which can be caused by the huge chemical and structural differences between Bi$_2$Se$_3$ and GaN. A polycrystalline film may also be instigated by the low diffusivity of adatoms on GaN, for which adatom-substrate interaction is expectedly strong due to possible chemical bonding. Nuclei of Bi$_2$Se$_3$ can be strained by the constraint of the substrate lattice. The strained Bi$_2$Se$_3$ nuclei or crystallites are likely distorted and twisted and their coalescence will produce a polycrystalline layer. The coexistence in Fig. 1(b) of the streaky and ring patterns, on the other hand, suggests both “epitaxial” Bi$_2$Se$_3$ domains (where the c-axis of Bi$_2$Se$_3$ aligns with the surface normal of GaN(0001)) and randomly oriented crystallites to coexist. The receding ring pattern accompanied by the enhancement of the streaky pattern with increasing deposition thickness [Fig. 1(c)] implies the improvement of the film quality with thickness.

We note that even for very thick films, they remain highly “in-plane” textured. Changing the azimuthal angle of the RHEED shows little change of the diffraction patterns except for small intensity variations. The sample must thus contain randomly oriented domains in the “in-plane” directions despite that they are well aligned in the “out-of-plane” (i.e., the c-axis) direction for thick layers. The texturing of epitaxial Bi$_2$Se$_3$ on GaN is best revealed in the low-energy electron diffraction (LEED) pattern shown in Fig. 1(d), in which a circular ring rather than diffraction spots are observed despite the slight variation in intensity along the ring. The latter implies some preferred in-plane crystallographic orientations to exist, which becomes clearer and more pronounced if one adopts the so called “two-step” deposition process as pointed out in an early publication.

The improvement of crystal quality of Bi$_2$Se$_3$-on-GaN with increasing film thickness, from the initial polycrystalline to finally an in-plane textured film, may be understood by considering the anisotropic growth rates of Bi$_2$Se$_3$ crystal faces. Given a small crystallite, the c-plane, which is of the vdW surface, has no dangling bond and thus the lowest surface energy. On the contrary, the other faces inclined to the c-plane have high energies. As the crystallite develops, the low-energy surface will grow at the expense of the high-energy planes. Kinetically, atoms adsorbed on the c-face diffuse faster and can always reach the “edges” where they become incorporated in crystal. So, a crystallite will grow predominantly sideways, leading to the enlargement of the c-face. If a crystallite has its c-plane parallel to the substrate surface, it receives the largest amount of the deposit atoms from the flux and so grows faster. For those where their c-faces are inclined to the substrate surface, they receive fewer atoms from the flux and thus grow slower. Ultimately, crystallites with their c-planes parallel to GaN(0001) prevail and the epifilm becomes aligned along the c-axis out of the initially randomly oriented crystallites in the nucleation layer.

The kinetics can be characteristic of growth of other layered materials where the c-plane is always the growing surface even if the substrate is not of the low-index surface. In-plane lattice alignment of the epifilm, on the other hand, has to be driven by other factors such as the energy potentials of the vdW interface. The latter is generally a weaker effect in vdW epitaxy, so heeling of in-plane texturing can be a much slower process.

On graphene, Bi$_2$Se$_3$ growth follows a much simpler process, which does not go through the initial polycrystalline stage. Figs. 2(a)–2(c) record the evolution of the RHEED patterns during Bi$_2$Se$_3$ deposition on multilayer graphene formed by heating SiC. As seen, upon the commencement of Bi$_2$Se$_3$ deposition, streaky RHEED patterns corresponding to a strain-free Bi$_2$Se$_3$ emerge in the background of the graphene pattern [Fig. 2(b)]. After about 1 QL growth, only the Bi$_2$Se$_3$ pattern becomes visible. Unlike that on GaN, Bi$_2$Se$_3$ on graphene is not very textured. In-plane alignment of [1010]$_{\text{Bi}_2\text{Se}_3} || \ [1010]_{\text{Graphene}}$ is identified, though 30° rotation domains are also present as revealed in the RHEED and

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**FIG. 1.** (a)–(c) RHEED patterns of, respectively, the substrate (GaN), ~1 QL and 40 QLs of Bi$_2$Se$_3$ surfaces. (d) LEED pattern of the 40 QLs Bi$_2$Se$_3$ grown on GaN. The vertical arrows in (a)–(c) mark the 1st-order diffraction streaks of the substrate or epitaxial Bi$_2$Se$_3$. The inclined yellow arrow points at the polycrystalline ring.
As will be shown later, epitaxial Bi$_2$Se$_3$ is strain-free on graphene, establishing a bond. Deposit-substrate interaction is expectedly weak. Where a tensile strain is recorded. Unstrained Bi$_2$Se$_3$ nuclei initially grow on graphene from the very beginning, contrasting that on GaN, even for thin films. From the flat terraces, indicating bunches of screw dislocations. On graphene, on the other hand, one sees large triangular islands or mounds [Fig. 3(c)]. Importantly, few multi-QL high steps are seen from the flat terraces. Instead, one observes single QL steps (e.g., pointed by the black arrow in Fig. 3(d)) that emerge from the flat terraces and manifest as spirals, signaling growth at single and isolated screw dislocations, or the specific step pinning mechanism of the step-growth. The latter film is obviously less twisted or tilted, consistent with the early RHEED observations.

Having discussed the structural and morphological properties of epitaxial Bi$_2$Se$_3$ on GaN versus graphene, we now shift our attention to the lattice constant and strain evolution during initial stage Bi$_2$Se$_3$ deposition on the two substrates. Figs. 4(a) and 4(b) depict film thickness (or deposition time) dependence of the in-plane lattice constant (a) of the deposits as derived by Eq. (1) from the measured inter-streak spacing D of the RHEED. As is seen, on graphene (red curve), epitaxial Bi$_2$Se$_3$ is strain-free from the very beginning, whereas on GaN (black curve), it is ε ~ 3% tensile strained for the initially deposited Bi$_2$Se$_3$ layer. Here, strain ε is defined as ε = (a - a$_0$)/a$_0$, where a$_0$ refers to the lattice constant of strain-free Bi$_2$Se$_3$, and a is derived from Eq. (1). The tensile strain relaxes gradually to the bulk crystal lattice constant with increasing thickness on GaN. We remark that the ~3% strain measured by the RHEED is significant, well above the resolution limit (~0.3%) of our RHEED measurement estimated by statistical analyses and by experimental observation of the lattice constant variation with temperature.

Epitaxial growth of Bi$_2$Se$_3$ on graphene represents an example of the vdW epitaxy, where deposit-substrate interaction is weak at the interface. An unstrained epitfilm is therefore expected. The fact that the (in-plane) lattice constant of sub-QL Bi$_2$Se$_3$ on graphene is the same as that of the bulk crystal suggests that single QL clusters or islands has the same equilibrium lattice constant as the bulk crystal. This appears inconsistent with a recent report of an intrinsically enlarged lattice constant of ultrathin Bi$_2$Se$_3$ layer grown on Si, reflecting possibly a substrate effect. The observed lattice stretching of Bi$_2$Se$_3$ on GaN can, on the other hand, be attributed to the constraint of the substrate lattice due to a strong heterointerface interaction. As noted earlier, although textured, the deposited Bi$_2$Se$_3$ on GaN still
In summary, we have followed the initial stage Bi$_2$Se$_3$ deposition on two very different substrates, GaN and graphene, and revealed distinct growth properties and the strain states of the epifilms. While it is tensile-strained on GaN, epitaxial Bi$_2$Se$_3$ is strain-free from the beginning on graphene. Accompanied with this is the difference in morphology and the crystallinity of the epifilms, which is better on graphene substrate. These differences may be accounted for by the different interaction strengths between the deposit and the substrate. The above results may be extended to other vdW versus covalent substrates. Manipulating strain in a TI film is attractive for tuning the topological states, which is thus of great fundamental and practical interests for further studies.

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